WHAT IS CLAIMED IS:

1. A hand for holding a substrate comprising:

a hand main body; and

a plurality of seating members mounted on the hand main body and on which the substrate is to be seated, wherein

each of the plurality of seating members includes a shaft member and a lever member, the shaft member is supported to the hand main body, the lever member is supported to the shaft member and has a first end portion and a second end portion, the first end portion includes a seating portion on which the substrate is to be seated, and the second end portion is disposed on a side opposite to the first end portion across the shaft member, and

at least a part of the plurality of seating members further includes a biasing member and a seating sensor, the biasing member is for giving a force of rotating the lever member to the lever member such that the second end portion moves downward, and the seating sensor is configured to detect an upward movement of the second end portion.

2. The hand according to claim 1, wherein

a magnet is disposed on the second end portion of the lever member, and

the seating sensor includes a magnetic sensor configured to detect an upward movement of the magnet.

3. The hand according to claim 1, wherein

the seating sensor includes an optical sensor that includes a light projecting component and a light receiving component, and

the lever member is supported to the shaft member so as to block between the light projecting component and the light receiving component when the second end portion moves upward.

4. The hand according to claim 1, wherein

a first electric contact is disposed on the second end portion of the lever member, and

the seating sensor includes an electric sensor that includes a second electric contact in

contact with the first electric contact when the second end portion moves upward.

5. The hand according to claim 1 ~~any one of claims 1 to 4~~, wherein

at least a part of the plurality of seating members further includes a housing configured to cover the second end portion of the lever member and the seating sensor.

6. The hand according to claim 1~~any one of claims 1 to 5~~, wherein

the plurality of seating members are mounted on the hand main body at predetermined intervals with one another so as to surround a seating region on which the substrate is to be seated, and

the lever member is supported to the shaft member such that the first end portion projects to the seating region.

7. The hand according to claim 1 ~~any one of claims 1 to 6~~, wherein

each of the plurality of seating members includes a bearing and an elastic member, the bearing is for supporting both end portions of the shaft member, and the elastic member is for supporting the bearing.

8. The hand according to claim 1~~any one of claims 1 to 7~~, further comprising:

a plurality of guiding members mounted on the hand main body at predetermined intervals with one another so as to surround a seating region on which the substrate is to be seated; and

a plurality of positioning members mounted on the hand main body at predetermined intervals with one another so as to surround the seating region, wherein

each of the plurality of guiding members has a substrate receiving surface inclined downward toward the seating region, and

each of the plurality of positioning members includes a positioning portion in contact with an outer edge of the seating region.

9. The hand according to claim 8, wherein

each of the plurality of positioning members includes a positioning post formed in a columnar shape.

10. The hand according to claim 1~~any one of claims 1 to 9~~, further comprising:

a supporting member for supporting the hand; and

a hand support for mounting the hand on the supporting member, wherein

the hand support includes a first hand support and a second hand support, the first hand support is mounted on any one of the hand and the supporting member, and the second hand support is mounted on another one of the hand and the supporting member,

a bottom surface of the first hand support has a tapered surface inclined to taper off toward the second hand support, and

the second hand support has a coupling region into which the first hand support is inserted, and the coupling region has a tapered surface inclined corresponding to the tapered surface of the first hand support.

11. The hand according to claim 10, wherein

a cutout is formed in a side surface on a side of the second hand support of the first hand support, and

the coupling region includes a protrusion having a tapered surface inclined corresponding to a tapered surface formed in the cutout.

12. A transfer apparatus comprising:

the hand according to claim 1~~any one of claims 1 to 11~~; and

a driving mechanism for moving the hand.

13. A substrate processing apparatus comprising:

a polishing device configured to polish a substrate;

a cleaning device configured to clean the substrate; and

the transfer apparatus according to claim 12 configured to transfer the substrate processed by the polishing device or the cleaning device.

14. The hand according to claim 1, further comprising:

a plurality of guiding members mounted on the hand main body at predetermined intervals with one another so as to surround a seating region on which the substrate is to be seated; and

a plurality of positioning members mounted on the hand main body at predetermined

intervals with one another so as to surround the seating region, wherein

each of the plurality of guiding members has a substrate receiving surface inclined downward toward the seating region, and

each of the plurality of positioning members includes a positioning portion in contact with an outer edge of the seating region.

15. A hand for holding a substrate comprising:

a hand main body; and

a plurality of seating members mounted on the hand main body and on which the substrate is to be seated, wherein

each of the plurality of seating members includes a shaft member, a lever member, a bearing, and an elastic member, the shaft member is supported to the hand main body, the lever member is supported to the shaft member and has a first end portion and a second end portion, the first end portion includes a seating portion on which the substrate is to be seated, and the second end portion is disposed on a side opposite to the first end portion across the shaft member, the bearing is for supporting both end portions of the shaft member, and the elastic member is for supporting the bearing.

16~~15~~. The hand according to claim 15~~14~~, wherein

the bearing includes a pair of bearings for supporting respective both the end portions of the shaft member, and

the elastic member includes a pair of elastic members for supporting the respective pair of bearings.

17~~16~~. The hand according to claim 15~~14~~, wherein

the bearing includes a single bearing extending across both the end portions of the shaft member below the shaft member, and

the elastic member includes a single elastic member configured to support a center of a lower surface of the single bearing.

~~17. The hand according to any one of claims 14 to 16, wherein~~

~~at least a part of the plurality of seating members includes a biasing member and a~~

~~seating sensor, the biasing member is for giving a force of rotating the lever member to the lever member such that the second end portion moves downward, and the seating sensor is configured to detect an upward movement of the second end portion.~~

~~18. The hand according to claim 17, wherein~~

~~a magnet is disposed on the second end portion of the lever member, and~~

~~the seating sensor includes a magnetic sensor configured to detect an upward movement of the magnet.~~

~~19. The hand according to claim 17, wherein~~

~~the seating sensor includes an optical sensor that includes a light projecting component and a light receiving component, and~~

~~the lever member is supported to the shaft member so as to block between the light projecting component and the light receiving component when the second end portion moves upward.~~

~~20. The hand according to claim 17, wherein~~

~~a first electric contact is disposed on the second end portion of the lever member, and~~

~~the seating sensor includes an electric sensor that includes a second electric contact in contact with the first electric contact when the second end portion moves upward.~~

~~21. The hand according to any one of claims 17 to 20, wherein~~

~~at least a part of the plurality of seating members further includes a housing configured to cover the second end portion of the lever member and the seating sensor.~~

~~22. The hand according to any one of claims 14 to 21, wherein~~

~~the plurality of seating members are mounted on the hand main body at predetermined intervals with one another so as to surround a seating region on which the substrate is to be seated, and~~

~~the lever member is supported to the shaft member such that the first end portion projects to the seating region.~~

~~23. The hand according to any one of claims 14 to 22, further comprising:~~

~~a plurality of guiding members mounted on the hand main body at predetermined~~

~~intervals with one another so as to surround a seating region on which the substrate is to be seated; and~~

~~a plurality of positioning members mounted on the hand main body at predetermined intervals with one another so as to surround the seating region, wherein~~

~~each of the plurality of guiding members has a substrate receiving surface inclined downward toward the seating region, and~~

~~each of the plurality of positioning members includes a positioning portion in contact with an outer edge of the seating region.~~

~~24. The hand according to claim 23, wherein~~

~~each of the plurality of positioning members includes a positioning post formed in a columnar shape.~~

~~25. The hand according to any one of claims 14 to 24, further comprising:~~

~~a supporting member for supporting the hand; and~~

~~a hand support for mounting the hand on the supporting member, wherein~~

~~the hand support includes a first hand support and a second hand support, the first hand support is mounted on any one of the hand and the supporting member, and the second hand support is mounted on another one of the hand and the supporting member,~~

~~a bottom surface of the first hand support has a tapered surface inclined to taper off toward the second hand support, and~~

~~the second hand support has a coupling region into which the first hand support is inserted, and the coupling region has a tapered surface inclined corresponding to the tapered surface of the first hand support.~~

~~26. The hand according to claim 25, wherein~~

~~a cutout is formed in a side surface on a side of the second hand support of the first hand support, and~~

~~the coupling region includes a protrusion having a tapered surface inclined corresponding to a tapered surface formed in the cutout.~~

~~27. A transfer apparatus comprising:~~

~~the hand according to any one of claims 14 to 26; and~~

~~a driving mechanism for moving the hand.~~

~~28. A substrate processing apparatus comprising:~~

~~a polishing device configured to polish a substrate;~~

~~a cleaning device configured to clean the substrate; and~~

~~the transfer apparatus according to claim 27 configured to transfer the substrate processed by the polishing device or the cleaning device.~~

18~~29~~. A hand for holding a substrate, comprising:

a hand main body;

a plurality of seating members mounted on the hand main body and on which the substrate is to be seated;

a plurality of guiding members mounted on the hand main body at predetermined intervals with one another so as to surround a seating region on which the substrate is to be seated; and

a plurality of positioning members mounted on the hand main body at predetermined intervals with one another so as to surround the seating region, wherein

each of the plurality of guiding members has a substrate receiving surface inclined downward toward the seating region, and

each of the plurality of positioning members includes a positioning portion in contact with an outer edge of the seating region.

19~~30~~. The hand according to claim 18~~29~~, wherein

each of the plurality of positioning members includes a positioning post formed in a columnar shape.

~~31. The hand according to claim 29 or 30, wherein~~

~~each of the plurality of seating members includes a shaft member and a lever member, the shaft member is supported to the hand main body, the lever member is supported to the shaft member and has a first end portion and a second end portion, the first end portion includes a seating portion on which the substrate is to be seated, and the second end portion is~~

~~disposed on a side opposite to the first end portion across the shaft member, and~~

~~at least a part of the plurality of seating members further includes a biasing member and a seating sensor, the biasing member is for giving a force of rotating the lever member to the lever member such that the second end portion moves downward, and the seating sensor is configured to detect an upward movement of the second end portion.~~

~~32. The hand according to claim 31, wherein~~

~~a magnet is disposed on the second end portion of the lever member, and~~

~~the seating sensor includes a magnetic sensor configured to detect an upward movement of the magnet.~~

~~33. The hand according to claim 31, wherein~~

~~the seating sensor includes an optical sensor that includes a light projecting component and a light receiving component, and~~

~~the lever member is supported to the shaft member so as to block between the light projecting component and the light receiving component when the second end portion moves upward.~~

~~34. The hand according to claim 31, wherein~~

~~a first electric contact is disposed on the second end portion of the lever member, and~~

~~the seating sensor includes an electric sensor that includes a second electric contact in contact with the first electric contact when the second end portion moves upward.~~

~~35. The hand according to any one of claims 29 to 34, wherein~~

~~at least a part of the plurality of seating members further includes a housing configured to cover the second end portion of the lever member and the seating sensor.~~

~~36. The hand according to any one of claims 29 to 35, wherein~~

~~the plurality of seating members are mounted on the hand main body at predetermined intervals with one another so as to surround a seating region on which the substrate is to be seated, and~~

~~the lever member is supported to the shaft member such that the first end portion projects to the seating region.~~

~~37. The hand according to any one of claims 29 to 36, wherein~~

~~each of the plurality of seating members includes a bearing and an elastic member, the bearing is for supporting both end portions of the shaft member, and the elastic member is for supporting the bearing.~~

~~38. The hand according to any one of claims 29 to 37, further comprising:~~

~~a supporting member for supporting the hand; and~~

~~a hand support for mounting the hand on the supporting member, wherein~~

~~the hand support includes a first hand support and a second hand support, the first hand support is mounted on any one of the hand and the supporting member, and the second hand support is mounted on another one of the hand and the supporting member,~~

~~a bottom surface of the first hand support has a tapered surface inclined to taper off toward the second hand support, and~~

~~the second hand support has a coupling region into which the first hand support is inserted, and the coupling region has a tapered surface inclined corresponding to the tapered surface of the first hand support.~~

~~39. The hand according to claim 38, wherein~~

~~a cutout is formed in a side surface on a side of the second hand support of the first hand support, and~~

~~the coupling region includes a protrusion having a tapered surface inclined corresponding to a tapered surface formed in the cutout.~~

~~40. A transfer apparatus comprising:~~

~~the hand according to any one of claims 29 to 39; and~~

~~a driving mechanism for moving the hand.~~

~~41. A substrate processing apparatus comprising:~~

~~a polishing device configured to polish a substrate;~~

~~a cleaning device configured to clean the substrate; and~~

~~the transfer apparatus according to claim 40 configured to transfer the substrate processed by the polishing device or the cleaning device.~~